

Form PTO-1449  <b>INFORMATION DISCLOSURE CITATION IN AN APPLICATION</b>  (Use several sheets if necessary)	ATTY DOCKET NO. 2691-000013/US	APPLICATION NO. NEW APPLICATION
	APPLICANT(S) Kohshi TAGUCHI et al.	CONF. NO. Unknown
	FILING DATE January 7, 2005	GROUP Unknown

## U.S. PATENT DOCUMENTS

EXAMINER INITIAL	DOCUMENT NUMBER	DATE	NAME	CLASS	SUB CLASS	FILING DATE IF APPROPRIATE

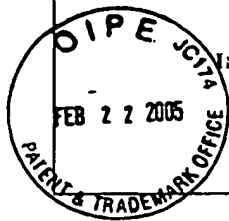
## FOREIGN PATENT DOCUMENTS

EXAMINER INITIAL	DOCUMENT NUMBER	DATE	COUNTRY	CLASS	SUB CLASS	TRANSLATION	
						YES	NO
HEA	JP 5-263255 A	10/12/1993	JAPAN				
HEA	EP 300447 A2	10/05/2001	EUROPE				
HEA	JP 9-41147 A	02/10/1997	JAPAN				

**OTHER DOCUMENTS** (Include Name of the author (in CAPITAL LETTERS), title of the article (when appropriate), title of the item (book, magazine, journal, serial, symposium, catalog, etc.) date, page(s), volume-issue number(s), publisher, city and/or country where published.


EXAMINER <i>Kendall Adams</i>	DATE CONSIDERED 9/27/05
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EXAMINER: Initial if citation considered, whether or not citation is in conformance with M.P.E.P. 609; Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.



FORM HDP-1449 (Based on Form PTO-1449)

PATENT AND TRADEMARK OFFICE  
INFORMATION DISCLOSURE CITATION  
(Use several sheets if necessary)

Sheet 1 of 1

ATTORNEY DOCKET NO.

2691-000013/US

SERIAL NO.

10/520,815

APPLICANTS

Kohshi TAGUCHI et al.

FILING DATE

January 7, 2005

GROUP

Unknown

## U.S. PATENT DOCUMENTS

Ref. Desig.	Examiner's Initials	Document Number	Date	Name	Class/ Subclass	(If appropriate) Filing Date
	HEA	US 5,508,067	04/16/1996	Tatsuya SATO et al.		
	HEA	US 5,591,494	01/07/1997	Tatsuya SATO et al.		

## FOREIGN PATENT DOCUMENTS

Ref. Desig.	Examiner's Initials	Document Number	Date	Country	Class/ Subclass	Translation Yes	No
	HEA	JP 2001-23904	01/26/2001	JAPAN		ABST.	
	HEA	JP 7-106256	04/21/1995	JAPAN		ABST.	
	HEA	JP 5-263255	10/12/1993	JAPAN		ABST.	
	HEA	EP 0 300 447 A2	01/25/1989	EUROPE		X	
	HEA	JP 9-41147	02/10/1997	JAPAN		ABST.	

## OTHER DOCUMENTS (including Author, Title, Date, Pertinent Pages, etc.)

Ref. Desig.	Examiner's Initials	
		Y. HATANAKA et al., "Remote plasma depositions of SiC <sub>x</sub> N <sub>y</sub> film using hexamethyldisilazane", Proc. of 6 <sup>th</sup> Int. Conf. Silicon Carbide and Related Materials Kyoto, IOP Conf., Ser. No. 142, Pages 1055-1058, 1995

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Examiner:

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9/27/05

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